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Testing of Thermally Actuated Rotational MEMS Mirror

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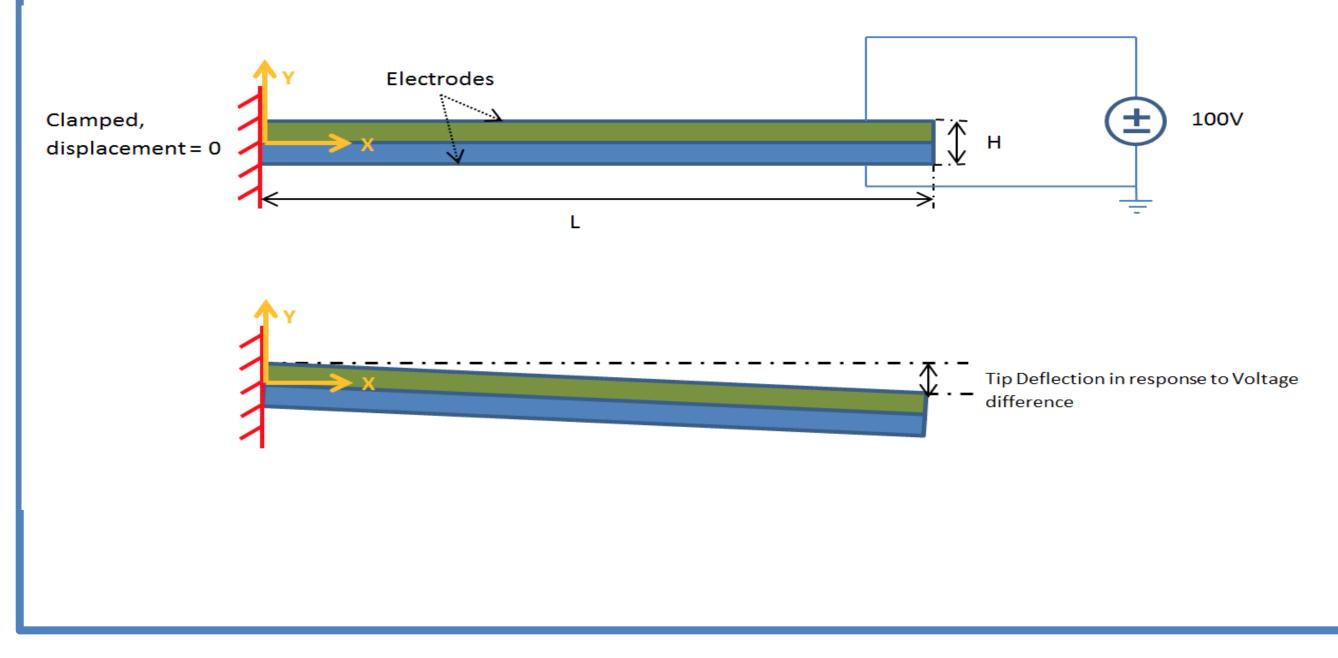
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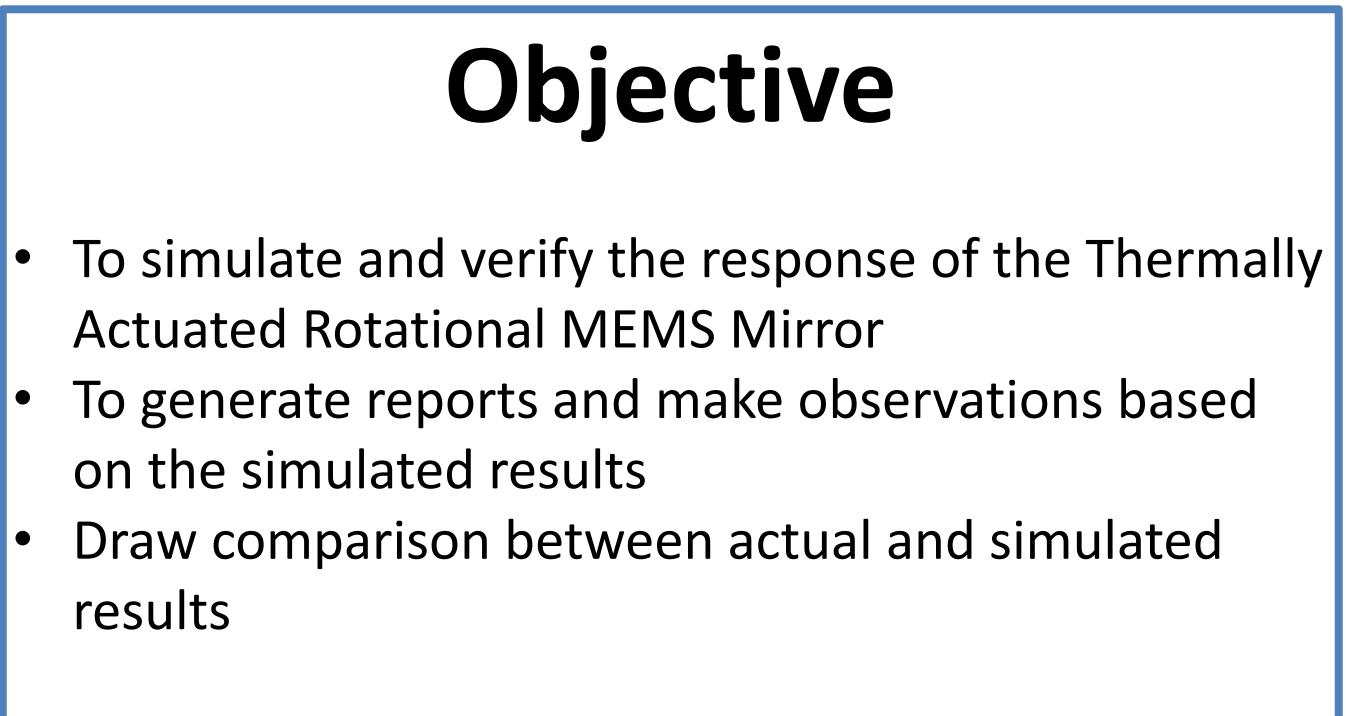


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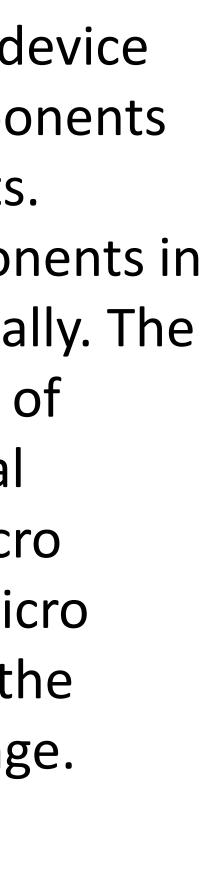
Introduction

A micro-electromechanical systems (MEMS) device contain both electrical and mechanical components that are in many common consumer products. Thermal micro actuators are standard components in micro systems and they are powered electrically. The thermal micro actuator shown below consist of material with different coefficients of thermal expansion. When the temperature of the micro actuator goes up due electrical power, the micro actuator changes shape due to difference in the expansion associated with temperature change.





Testing of Thermally Actuated Rotational MEMS Mirror By Shilen Parikh | Advisor: Dr. Guvench Department of Engineering | Sp. 2018



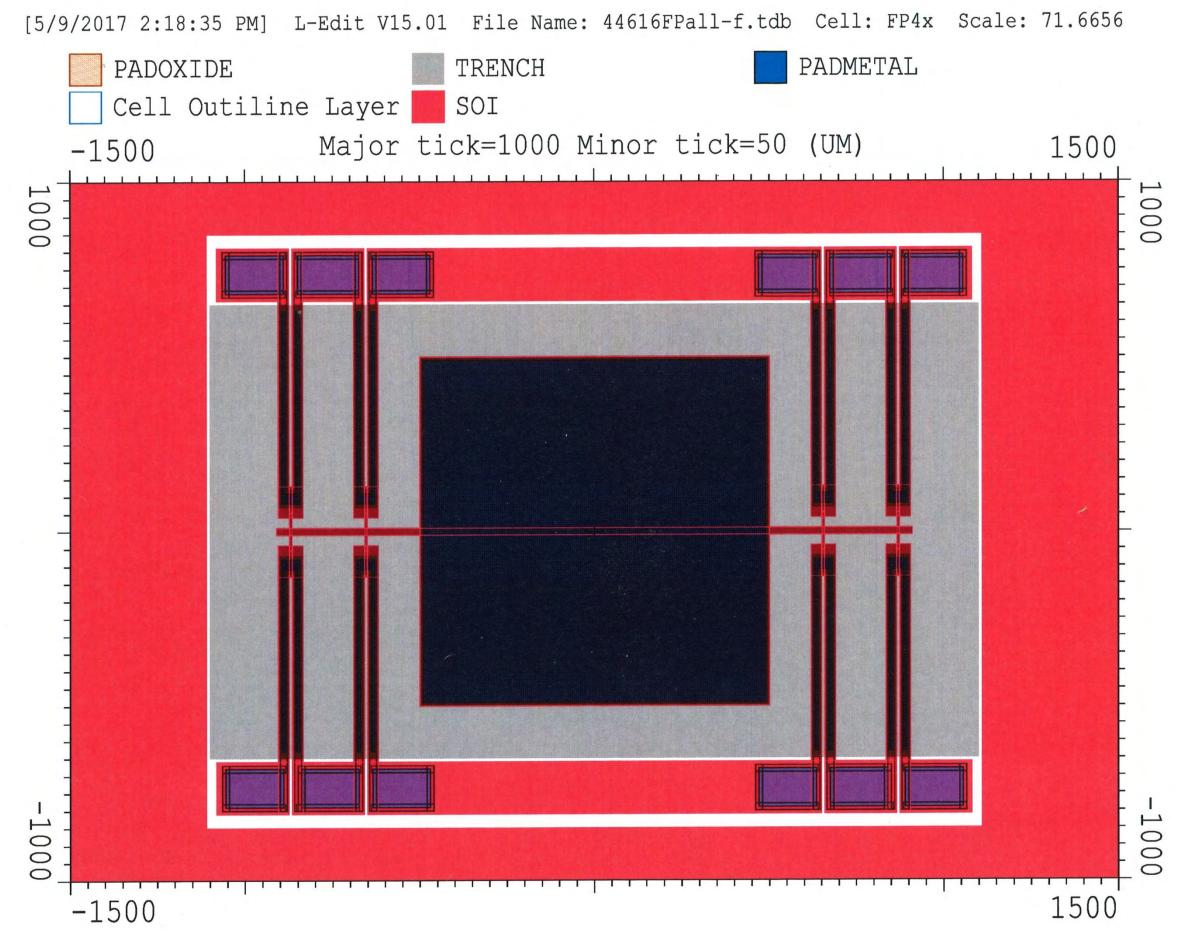


Figure 1: *MEMS L-Edit image*

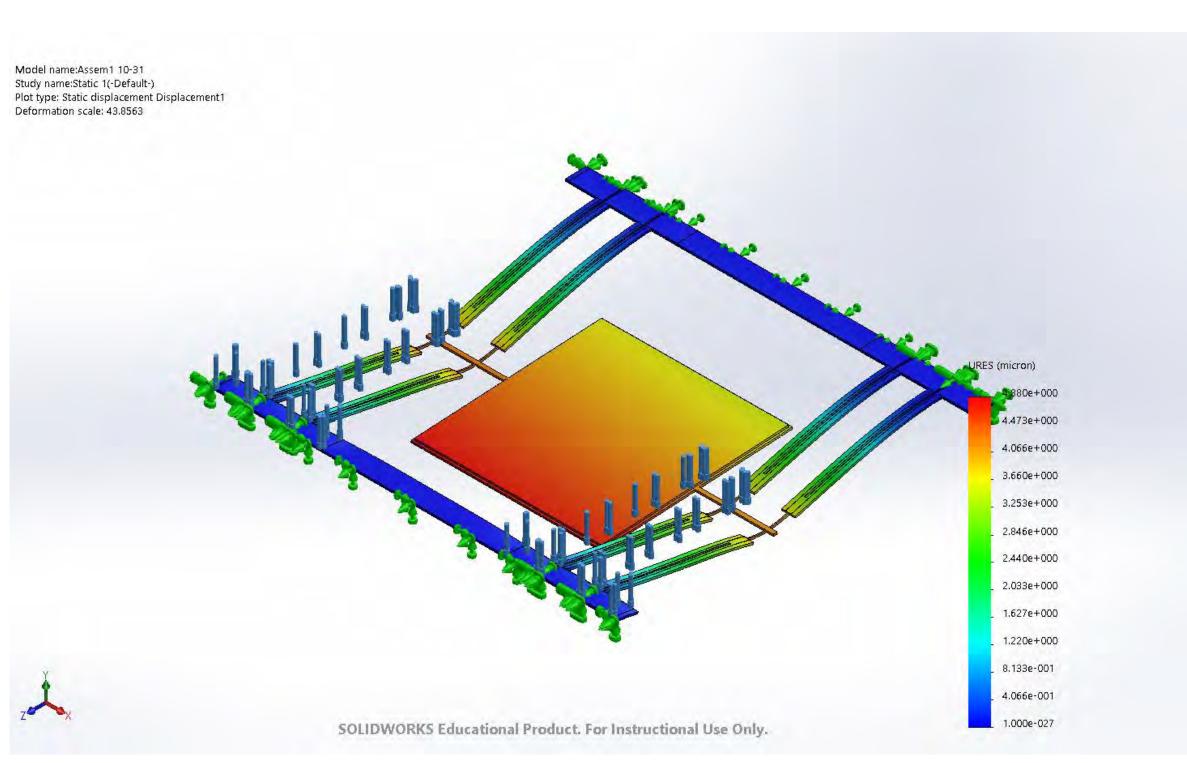


Figure 2: Solidworks simulation at 400 deg.C

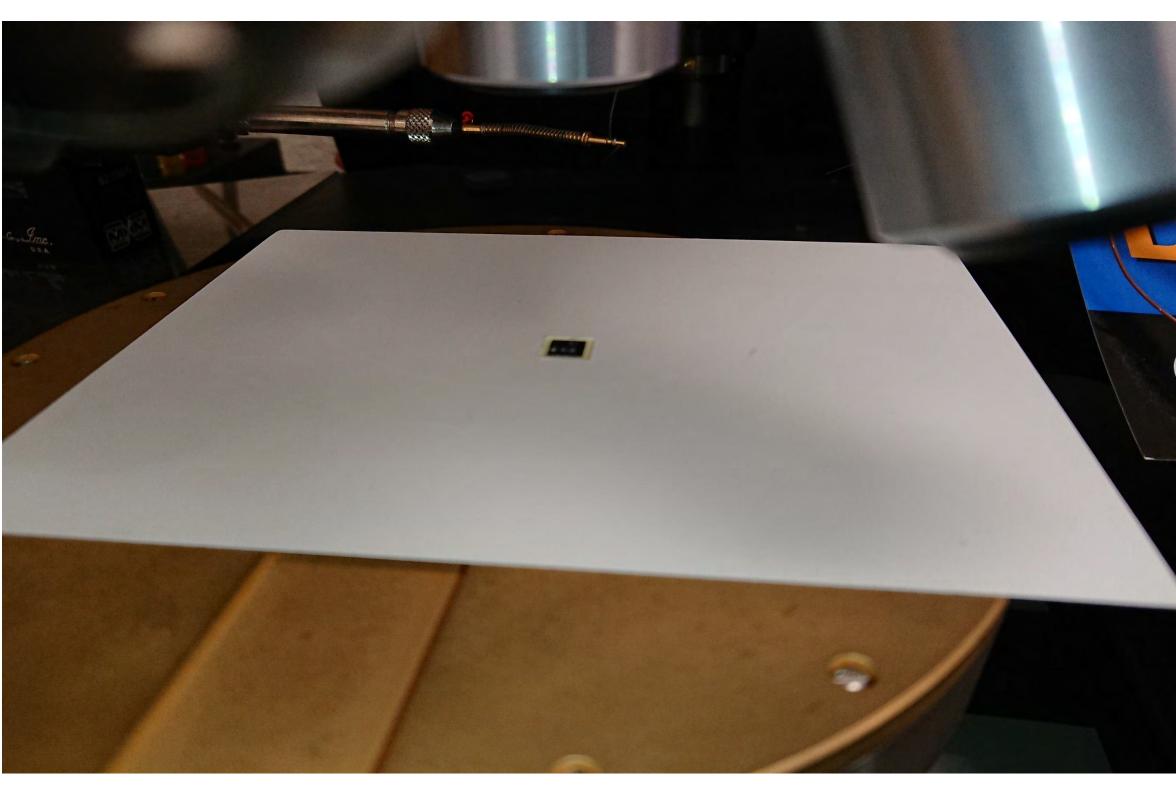
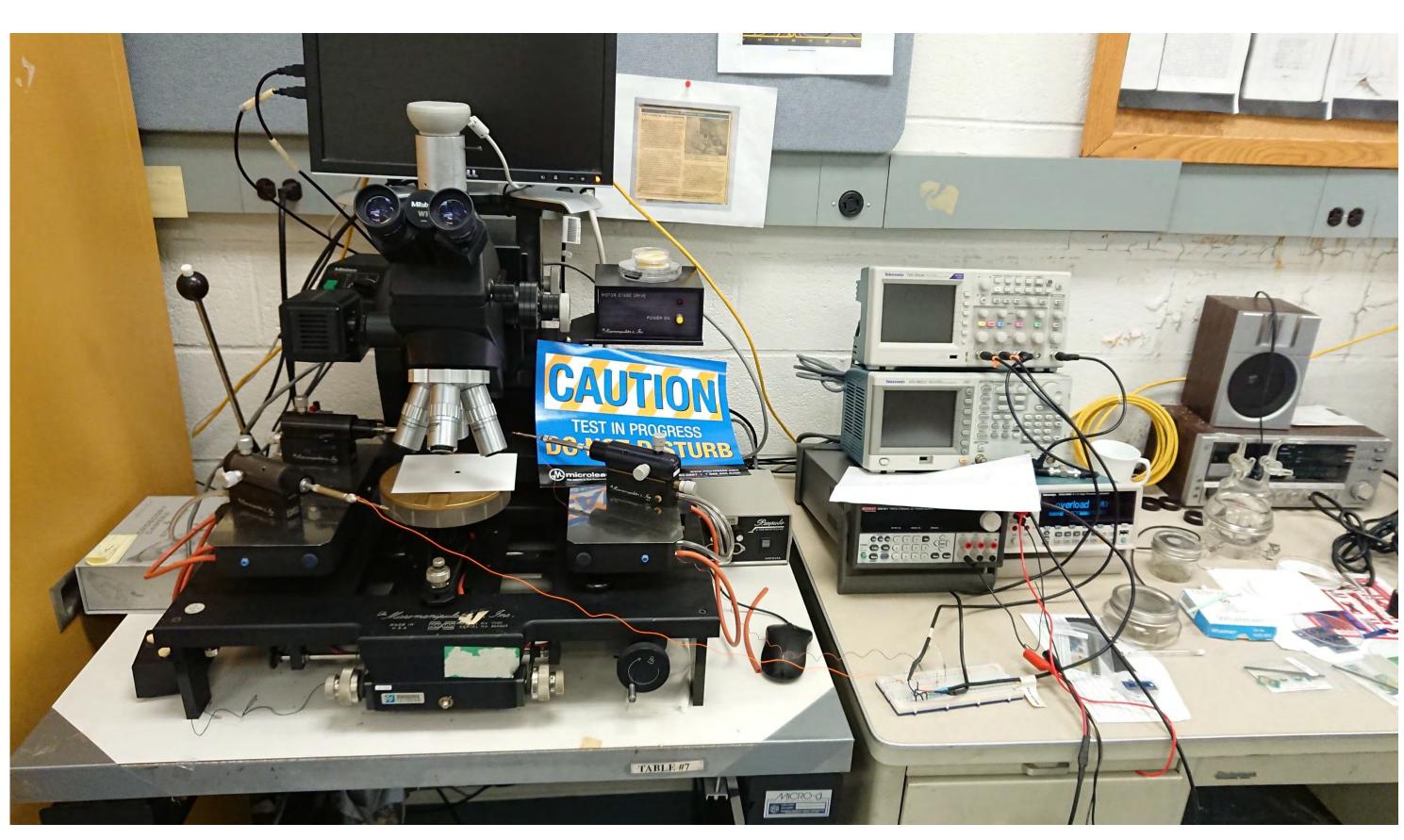


Figure 3: *Fabricated chip*

The device was first designed using L-Edit software. Using the L-Edit file, the MEMS chip was fabricated. This L-Edit design was used to test the finish product. However, before testing the fabricated chip, Solidworks software was used to do simulations based on various temperature environments and data was collected. Actual calculations were done using Excel to provide rough estimates of its intended functionally. Based on the results, the actual MEMS chip was tested.



The overall results generated from the simulation correlate well with the obtained data & figures from the fabricated MEMS chip.

Acknowledgements

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Design

Figure 4: Setup of MEMS chip

Conclusion